

Title (en)  
METHOD FOR MANUFACTURING AN OPTOELECTRONIC SENSOR

Title (de)  
VERFAHREN ZUR HERSTELLUNG EINES OPTOELEKTRONISCHEN SENSORS

Title (fr)  
PROCÉDÉ DE FABRICATION D'UN CAPTEUR OPTOÉLECTRONIQUE

Publication  
**EP 3432023 B1 20190814 (DE)**

Application  
**EP 18180276 A 20180628**

Priority  
DE 102017116492 A 20170721

Abstract (en)  
[origin: US2019022948A1] A method of manufacturing an optoelectronic sensor (10) is provided that has a reception unit (22) having a reception optics (24), a light receiver (28), and a diaphragm (26) therebetween, wherein the diaphragm (26) is arranged in a focal plane of the reception optics (24) so that a received light beam (20) generated by the reception optics is incident through the diaphragm aperture (42) of the diaphragm (26) at the point of smallest constriction. The diaphragm (26) is manufactured as an individual diaphragm using the reception optics (24).

IPC 8 full level  
**G01S 7/481** (2006.01); **G01S 7/497** (2006.01)

CPC (source: EP US)  
**B29C 64/393** (2017.07 - US); **B33Y 10/00** (2014.12 - US); **B33Y 50/02** (2014.12 - US); **B33Y 80/00** (2014.12 - US);  
**G01S 7/4816** (2013.01 - EP US); **G01S 7/497** (2013.01 - EP US)

Cited by  
EP3939774A1; DE202020101894U1; DE102020109596A1; DE102020109596B4; DE102020118941A1

Designated contracting state (EPC)  
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DOCDB simple family (publication)  
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